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AMENDMENT UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
GROUP 1765  
PATENT APPLICATION

AF/1765  
#10/C  
Hello  
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q61045

Fumiyoishi ONO

Appln. No.: 09/672,776

Group Art Unit: 1765

Confirmation No.: 2256

Examiner: Charlotte A. Brown

Filed: September 29, 2000

For: COMPOSITION FOR POLISHING METAL ON SEMICONDUCTOR WAFER AND  
METHOD OF USING SAME

**AMENDMENT UNDER 37 C.F.R. § 1.116**

ATTN: BOX AF  
Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated July 3, 2002, review and reconsideration  
on the merits are respectfully requested in view of the following amendments and  
remarks.

Please amend the above-identified application as follows:

**IN THE CLAIMS:**

**Please enter the following amended claims:**

6. (amended) A method for polishing a metal film on a semiconductor  
substrate, comprising the steps of:

providing a semiconductor substrate comprising a metal film and an insulating  
film therein;

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JUL 8 2002  
TC 1700

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